



Micro CMMs
SME MicroManufacturing Workshop
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Define Micro CMM

- **Small work volumes**
 - Typically 100mm x 100mm x 100mm
- **Fine positional accuracy**
 - <300nm
- **Low contact force**
 - <1mN



Commercial Options

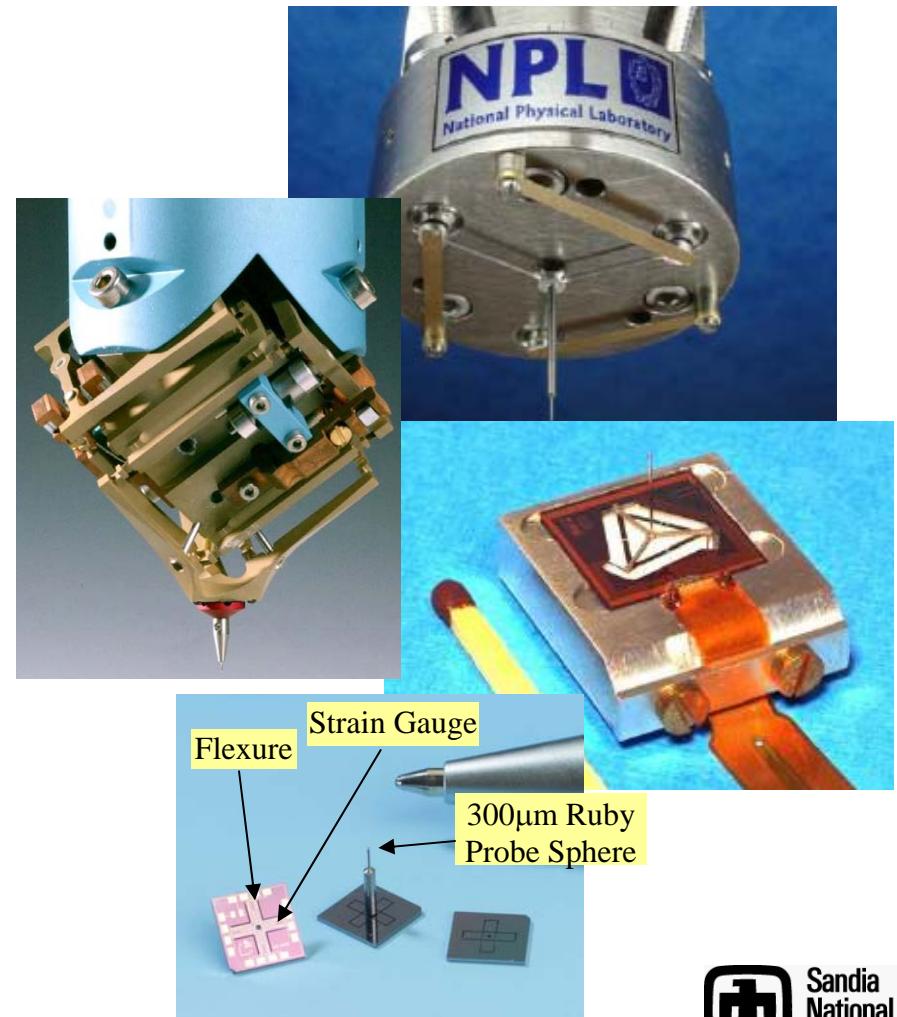
- **IBS**
 - ISARA
- **Mitutoyo**
 - UMAP
 - Nanocord
- **Zeiss**
 - F25
- **Non-commercial**
 - Many academic and NMI level projects





Contact Probing Technology

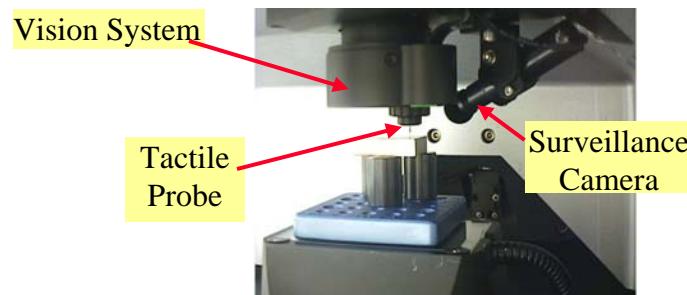
- MEMS Based
- Flexure / Capacitance
- Force gauges





Vision Probes

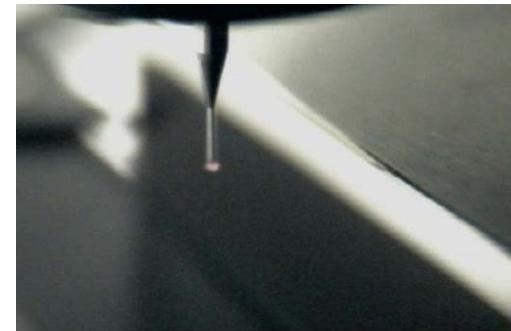
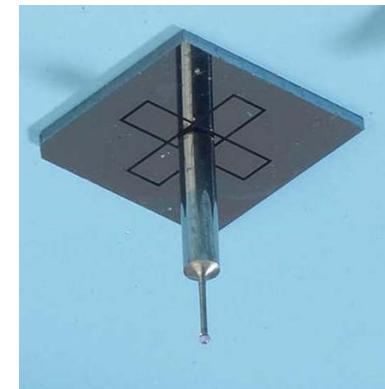
- **Most systems have both tactile and vision probing options**
- **Increases calibration complexity**
- **Registration of coordinate frames**





Probe Access

- Probe access is limited
- Gauging point (B89) on a gauge block inaccessible
- X-Z and Y-Z angles can be challenging





Calibration Concerns

- **Users should at least establish a verification procedure**
- **Optimally, users should be able to calibrate their own equipment**
- **Keep the tests simple (e.g., gauge blocks)**
 - Wringing skill



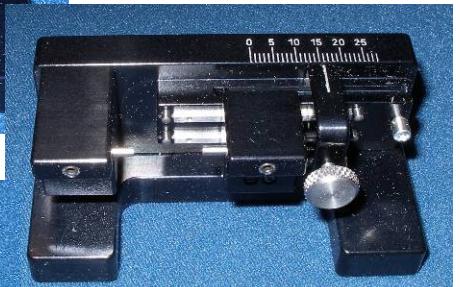
Operator Finesse

- **Checklists**
- **Change in attitude**
 - Much more technical
 - “Virtual” operation
- **Cleaning**
- **Heat transfer**
- **Everything matters**



Fixturing

- **Low contact forces**
- **No fixturing required?**
- **Best practice is to fixture parts**
- **Fixturing Options**
 - **Clay – No!**
 - **Clamps**
 - **Magnets**
 - **Cyanoacrylate**
 - **Low and High Viscosity**
 - **Hot glue**
 - **Thermals**





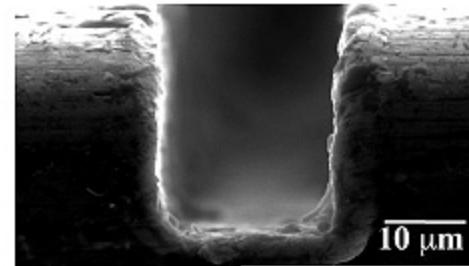
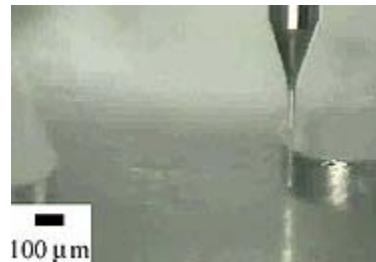
Important considerations for micro-CMMs

- **High purity cleaners**
 - Spectroscopic grade IPA
 - Spectroscopic grade Acetone
 - Caution
- **No canned/compressed air**
 - High force
 - Cools parts
- **Mechanical cleaning of probes may be done with extreme care**
- **Characterization of probe**
 - Full: Once per installation
 - Fine tune: Daily

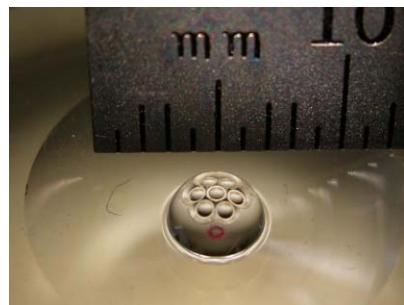
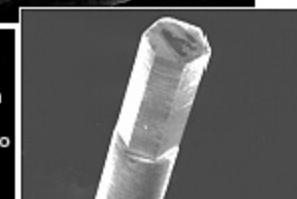


Sandia's Experience

- Sandia designs and manufactures a range of meso-scale components



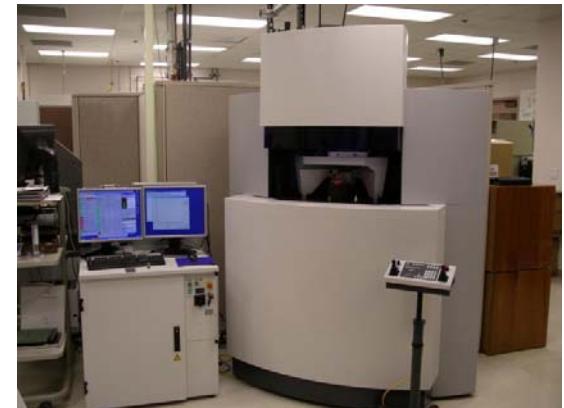
A 25- μm end mill tool (right), with five cutting edges, was fabricated using focused ion beam machining. The end mill was used to make this 25- μm deep channel (above) in aluminum.





SNL has acquired a micro-CMM.

- **Meso-scale manufacturing and system development area**
 - 10^1 mm in size
 - 10^{-1} mm features
 - 10^{-3} mm tolerances
- **MPE_E of $(0.250+L/666)\mu\text{m}$**
- **0.5mN probing force**
- **100mm x 100mm x 100mm work volume**
- **Tactile and vision probes**
- **Surveillance camera for operation**





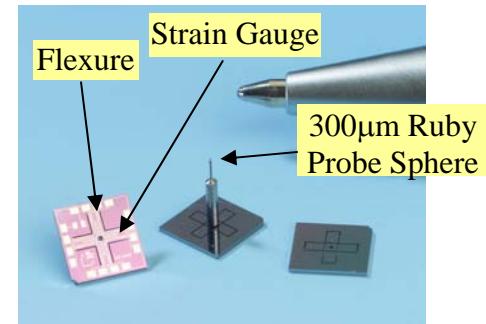
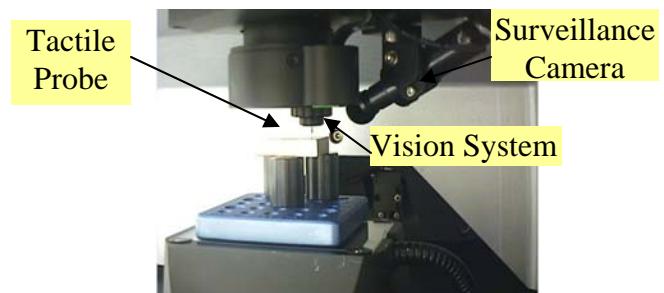
Precision design principles support accuracy claims by vendor

- Dual bridge design minimizes Abbe offsets
- Air bearing design modifications increases stiffness
 - >40 air bearings
- Vibration isolation
- Thermal shielding
- Glass scales
- Linear motors
 - Heat generation proportional to load



Silicon flexure tactile probe applies low contact force, ~0.5mN

- 120 μm and 300 μm diameter probes readily available
- Flexure + strain gauge sensing technology
 - Analog nature enables scanning
- Force-deflection response linearized during special calibration
- Max deflection is ~100 μm





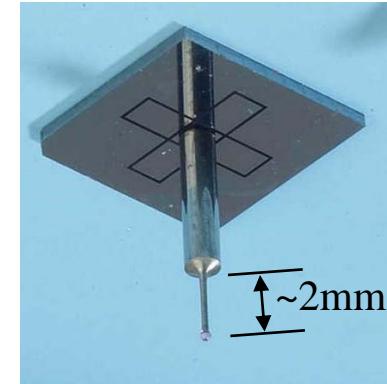
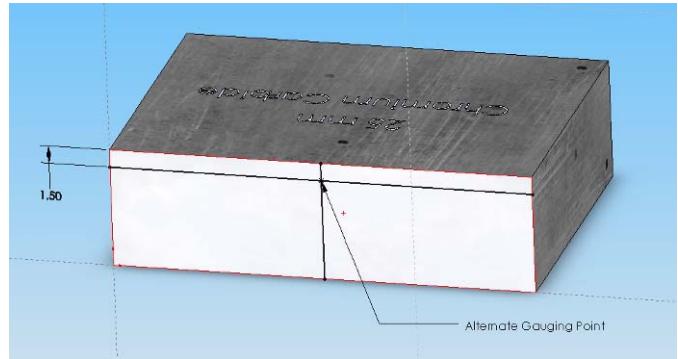
Force-Deflection Linearization Video

Probe Boss
Factor
Calibration



Evaluation requires special calibration of gauge blocks

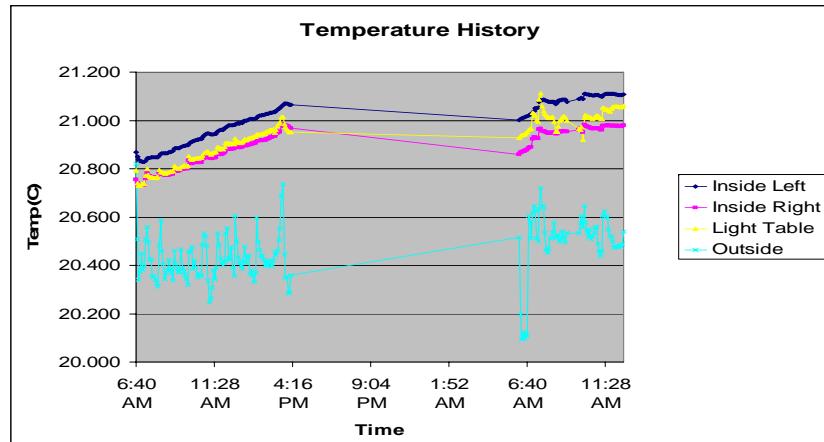
- **Shank length is approximately 2mm**
 - 300 μ m sphere / 200 μ m shaft
 - 120 μ m sphere / 50 μ m shaft
- **Unable to reach standard gauging point**
- **Alternate gauging point as shown (1.5mm down)**
- **Certification by SNL primary standards laboratory on gauge block interferometer**





Temperature and cleanliness are important at these levels

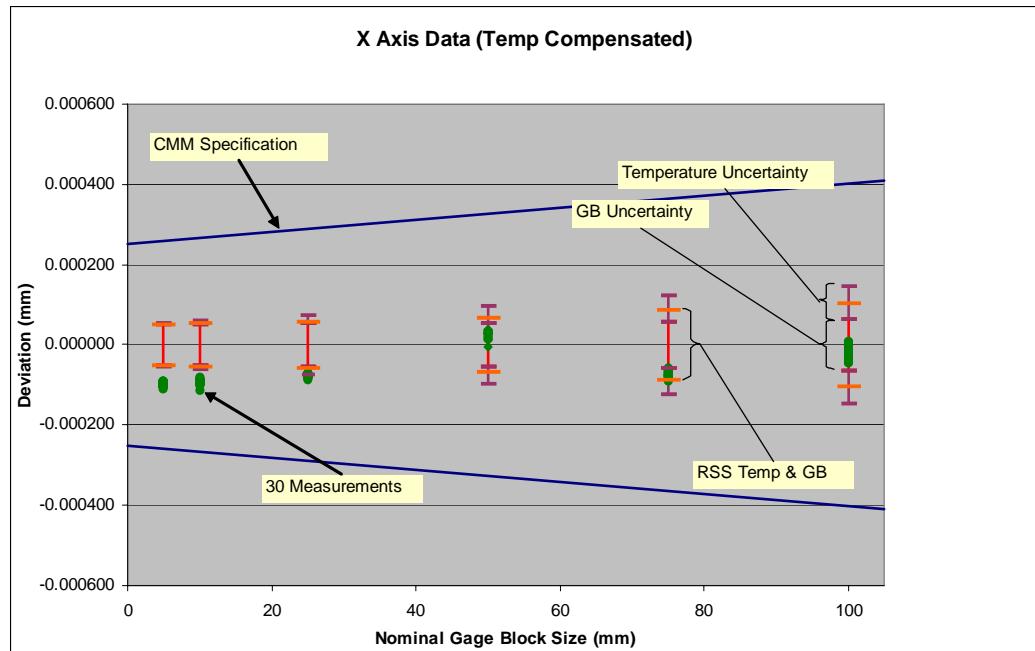
- Temperature
 - Absolute and gradient restrictions
 - Manual thermal compensation for this study
 - Minimize handling
- Cleaning
 - Spectroscopic grade IPA and acetone
 - Probe is delicate





X-Axis Results

- Excellent repeatability
- Well within specification



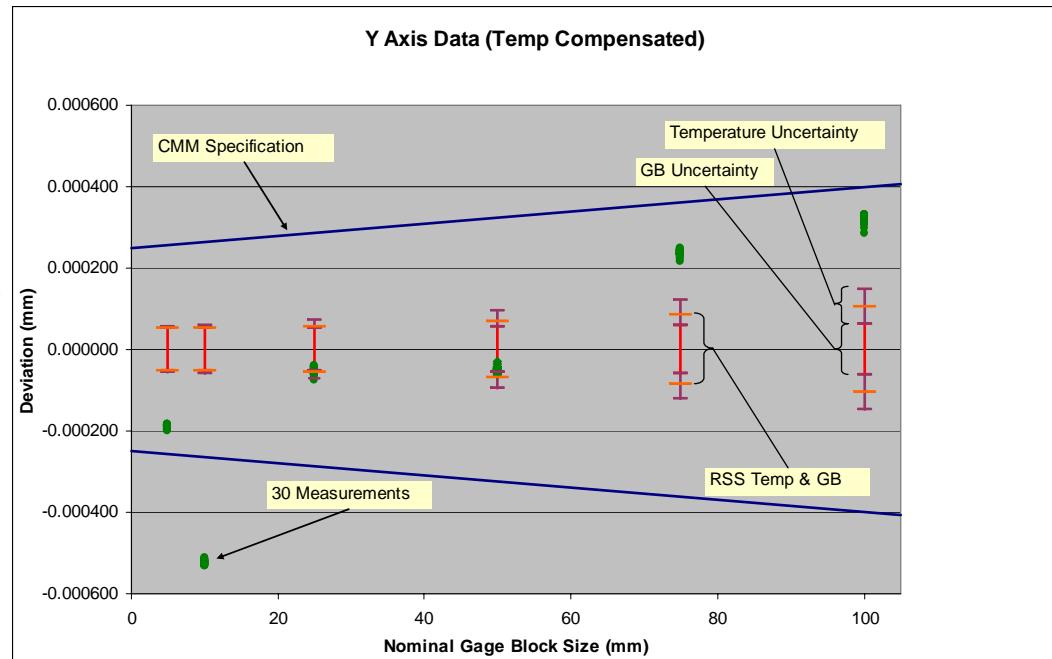
Temperature compensated x-axis results.

	5mm	10mm	25mm	50mm	75mm	100mm
Range	21 nm	32	16	45	32	54
Average	-98 nm	-93	-77	25	-74	-17
Std. Dev.	5 nm	6	4	10	7	16
F25 Spec +/-	258 nm	265	288	325	363	400



Y-Axis Results

- Excellent repeatability
- One set of outliers
 - Dust?
 - Not supported by other measurements
- Balance within specification



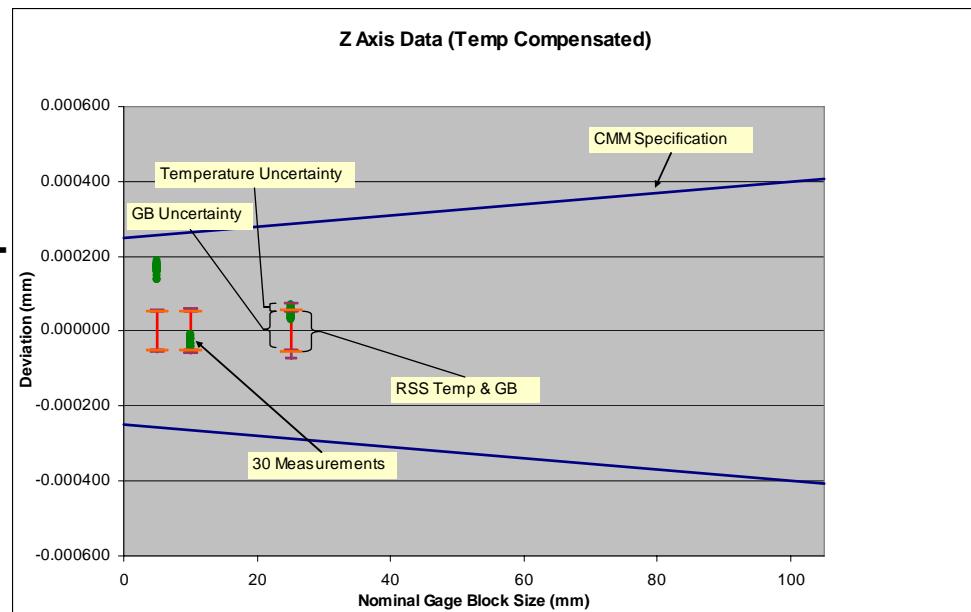
Temperature Compensated Y-Axis Results.

	5mm	10mm	25mm	50mm	75mm	100mm
Range	17 nm	22	37	33	35	49
Average	191 nm	-524	-54	-49	237	320
Std. Dev.	5 nm	5	8	7	7	11
F25 Spec +/-	258 nm	265	288	325	363	400



Z-Axis Results

- Mechanical constraints reduce gauge block set
- Sample repeatability as x- and y-axes
- Within specification



Temperature compensated z-axis data.

	5mm	10mm	25mm	50mm	75mm	100mm
Range	50 nm	45	41	NA	NA	NA
Average	168 nm	-31	49	NA	NA	NA
Std. Dev.	11 nm	12	12	NA	NA	NA
F25 Spec +/-	258 nm	265	288	325	363	400



Squareness Results

- 75mm gauge block in x-y plane
- 0.675 arcsec out-of square

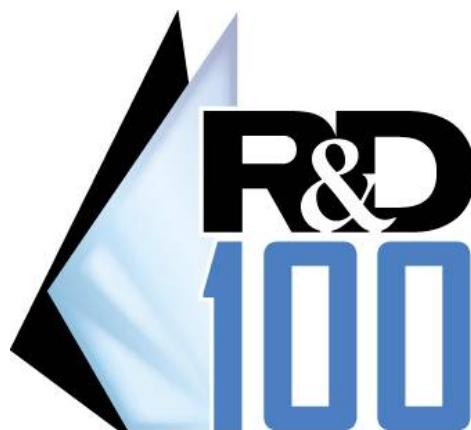
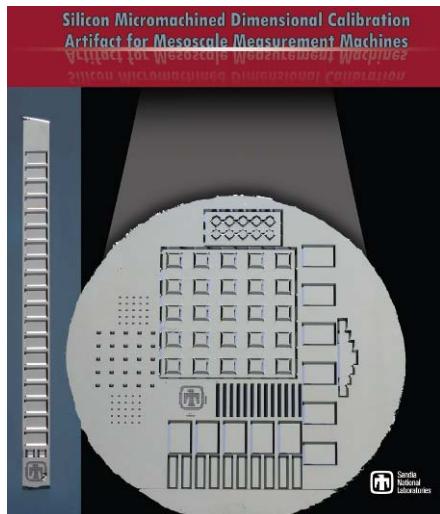
Squareness data.

	75mm (+X,+Y)	75mm (-X,+Y)
Range	21 nm	63
Average	-205 nm	286
Std. Dev.	5 nm	14



Advanced Calibration and Tactile/Vision Registration

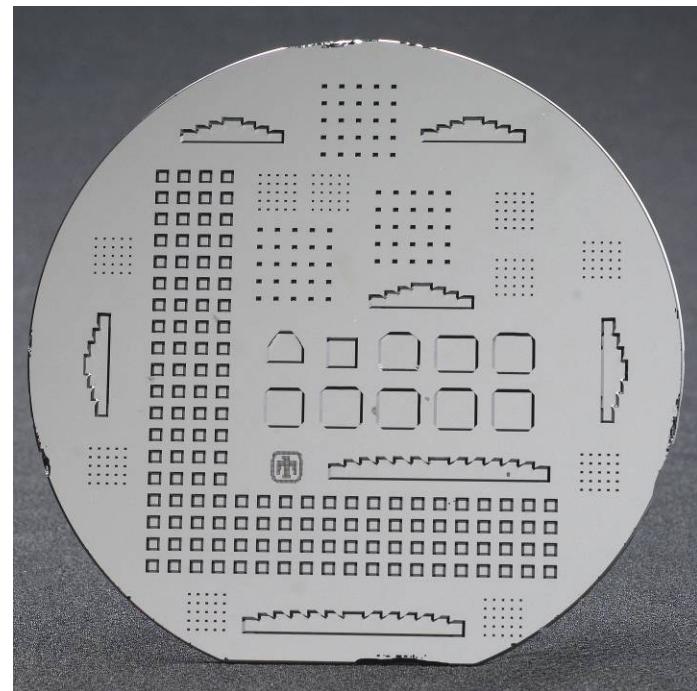
- R&D effort to improve calibration
- Silicon bulk micromachining
- Take advantage of crystal structure intrinsic properties
- 2008 R&D 100 Award Winner





Design Details

- Bulk-etched Si
 - $<100>$, gives sidewalls 54.74 degrees from horizontal
 - 1.5 mm thick wafer, polished on both sides
 - KOH etchant
- Geometric Features
 - “step gages”
 - “ball plates”
 - Additional shapes





Final Points

- Jump from traditional to micro CMMs larger than expected
- Probes are expensive
- Opportunity to train a new operator
- Clean, clean, clean
- Checklists
- Video capture for surveillance camera
 - Additional surveillance cameras



Discussion
